NOTES:

- 1. SUBSTRATE: Fused Silica
- 2. SURFACE S1 TO BE PARALLEL TO SURFACE S2 TO WITHIN <3 ARCMINS
- 3. COATING (APPLY ACROSS COATING APERTURE)

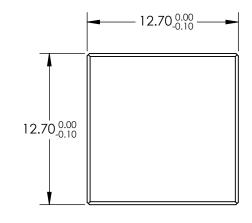
\$1: R(ABS) >99.8% @ 532nm R(ABS) >99.5% @ 523 - 537nm DAMAGE THRESHOLD, PULSED: 15 J/cm² @ 532nm, 20ns, 20Hz CW: 1 MW/cm² @ 532nm

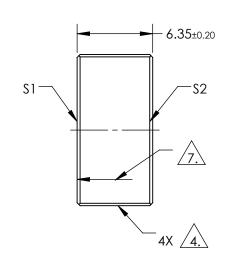
S2: NONE

FINE GROUND SURFACE

- 5. CLEAR APERTURE AND COATING APERTURE ARE CENTERED ON SURFACE
- POWER, IRREGULARITY, AND SURFACE QUALITY SPECIFICATIONS APPLY ACROSS CLEAR APERTURE

ARROW ON EDGE WITH LASER ETCH, PENCIL, OR PERMANENT INK POINTS TOWARDS SURFACE S1





PARTS TO THIS DRAWING

SPECIFICATIONS SUBJECT TO CHANGE WITHOUT NOTICE DIMENSIONS ARE FOR REFERENCE ONLY

	S1	S2	1			
SHAPE	PLANO	PLANO			Edmund Ontid	CC®
SURFACE QUALITY	10-5	COMMERCIAL POLISH		U	Edmund Option	\mathbf{CS}°
SURFACE FLATNESS	0.10 WAVE	N/A			12.7 x 12.7mm 532nm 45°, Nd:YAG La	sar Lina
MIN CLEAR APERTURE	10.80 x 10.80	N/A	THIRD ANGLE PROJECTION	TITLE	Mirror	SCI LIIIC
MIN COATNG APERTURE	10.80 x 10.80	N/A			77.111.61	CHEET
BEVEL	PROTECTIVE AS NEEDED	PROTECTIVE AS NEEDED	ALL DIMS IN mm	DWG NO	39641	SHEET 1 OF 1